

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Filing Date July 13, 2001 Assignee Micron Technology, Inc. Examiner Fuller, Eric B. Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate Comprising Dielectric Layers

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

To:

Assistant Commissioner for Patents

Washington, D.C. 20231

From:

Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)

Wells St. John P.S.

601 W. First Avenue, Suite 1300

Spokane, WA 99201-3828

Dear Sir:

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449 and copies of which are attached.

Citation of these references is respectfully requested.

A check in the amount of \$180.00 is enclosed to cover the fee specified under 37 C.F.R. § 1.17(p).

Respectfully submitted,

Movember 7, 2002 By:

Jennifer J// Tavlør. Reg. No./48.711

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